

Changmin Lee

List of Publications by Year in descending order

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11
papers

267
citations

1684188
5
h-index

1372567
10
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11
all docs

11
docs citations

11
times ranked

583
citing authors

#	ARTICLE	IF	CITATIONS
1	Carrier-Type Modulation and Mobility Improvement of Thin MoTe ₂ . Advanced Materials, 2017, 29, 1606433.	21.0	158
2	Improved Data Retention of InSnZnO Nonvolatile Memory by H ₂ O-Treated Al ₂ O ₃ Tunneling Layer: A Cost-Effective Method. IEEE Electron Device Letters, 2016, 37, 1272-1275.	3.9	34
3	P-N Junction Diode Using Plasma Boron-Doped Black Phosphorus for High-Performance Photovoltaic Devices. ACS Nano, 2019, 13, 1683-1693.	14.6	23
4	Characteristics of an Amorphous Carbon Layer as a Diffusion Barrier for an Advanced Copper Interconnect. ACS Applied Materials & Interfaces, 2020, 12, 3104-3113.	8.0	21
5	Homogeneous molybdenum disulfide tunnel diode formed <i>via</i> chemical doping. Applied Physics Letters, 2018, 112, .	3.3	15
6	Effects of H ₂ High-pressure Annealing on HfO ₂ /Al ₂ O ₃ /In _{0.53} Ga _{0.47} As Capacitors: Chemical Composition and Electrical Characteristics. Scientific Reports, 2017, 7, 9769.	3.3	5
7	Novel Conductive Filament Metal-Interlayer-Semiconductor Contact Structure for Ultralow Contact Resistance Achievement. ACS Applied Materials & Interfaces, 2018, 10, 26378-26386.	8.0	5
8	Electrical properties of HfO ₂ /Al ₂ O ₃ dielectrics fabricated on In _{0.53} Ga _{0.47} As by using atomic layer deposition at low temperatures (100 - 200 °C). Journal of the Korean Physical Society, 2018, 72, 283-288.	0.7	3
9	Effect of H ₂ S pre-annealing treatment on interfacial and electrical properties of HfO ₂ /Si _{1-x} Gex (x =) Tj ETQq1 1 0,784314 rgBT /Ove	5.5	2
10	Electrical properties of the HfO ₂ /Al ₂ O ₃ dielectrics stacked using single- and dual-temperature atomic-layer deposition processes on In _{0.53} Ga _{0.47} As. Semiconductor Science and Technology, 2019, 34, 105018.	2.0	1
11	Shallow doping effect of ZnO treatment using atomic layer deposition process on p-type In _{0.53} Ga _{0.47} As. Journal Physics D: Applied Physics, 2018, 51, 245106.	2.8	0